

Abstract

The present invention relates to a microlens fabrication method for fabricating a non-global microlens from a multi-layer substrate. In the microlens fabrication method of the invention,
5 a first layer of a predetermined etching rate is formed first, and then a second layer is formed on the first layer. The second layer has a predetermined etching rate different from that of the first layer. A mask pattern in use for etching is formed on the second layer, and then the first and second layers are
10 etched to form a non-spherical lens contour therein.